



FIS920000149US1 (00750426AA)

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**BOX #AF**

**RESPONSE UNDER 37 C.F.R. § 1.116**  
**---EXPEDITE PROCEDURE---**  
**EXAMINING GROUP 1765**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of  
David C. Ahlgren et al.

Serial No.: 09/633,857

Group Art Unit: 1765

Filed: August 7, 2000

Examiner: R. Kunemund

For: IN-SITU MONITORING AND CONTROL OF GERMANIUM  
PROFILE IN SILICON-GERMANIUM ALLOY FILMS AND  
TEMPERATURE MONITORING DURING DEPOSITION OF  
SILICON FILMS

Commissioner for Patents  
United States Patent and Trademark Office  
P. O. Box 1450  
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**TC 1700**

AMENDMENT UNDER 37 C. F. R. §1.116

Sir:

In response to the Office Action mailed July 14,  
2003, please amend the above-identified application as  
follows:

Amendments to the specification begin on page  
2 of this paper.

No amendments to the claims are presented in  
this paper.

Remarks begin on page 3 of this paper.